







### **Development of a baseline vertex detector prototype for the CEPC**

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Circular Electron Position Collider

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#### OUTLINE

- Development of the pixel sensors
- Overview of the baseline vertex detector
- Beam test of the prototype
- Summary





#### **CEPC** vertex detector Requirement

resolution

impact parameter



#### Main requirement:

- ➢ First layer located at a radius: ~1.6 cm.
- > Single-point resolution : <3  $\mu$ m. ~16  $\mu$ m pixel pitch
- ➢ Material budget :<0.15% X0/layer.</p>
- > Power consumption: <<u>50</u> *mW/cm*<sup>2</sup>, *if air cooling used*

# CDR: critical to provide excellent



Hit Density vs. VXD Radius

Target: *small pitch, low power, light structure and high data rate.* 





### Timeline of Silicon Pixel sensor R&D



Ref: Jianchun Wang, Status of The CEPC Detector R&D, on CEPC workshop .



### **Monolithic Active Pixel Sensor**



Standard MAPS (ALPIDE, TaichuPix1)

MAPS is a promising candidate to meet the high speed, high granularity, small pitch and adequate radiation tolerance.

Small electrode of the 0.18  $\mu m$  technology

- Small sensor capacitance (<5 fF)
- A quadruple well technology
- Speed is limited by the depleted zone, a modified technology can be used to have a full depleted zone.
- Epitaxial layer with 25 µm and high resistivity of 1

 $k\Omega$ ·cm, improving the radiation hardness





#### TaichuPix sensor prototyping

- Major challenges for the CMOS sensor
  - Small pixel size  $\rightarrow$  high resolution (3-5 µm)
  - High readout speed (dead time < 500 ns @ 40 MHz ) → for CEPC Z pole</li>
  - Radiation tolerance : 1 Mrad TID
- Completed 3 round of sensor prototyping in CIS 180 nm process
  - Two MPW chips (5 mm  $\times$  5 mm )
    - TaichuPix1: 2019.06 2019.11
    - TaichuPix2: 2020.02 2020.06
  - 1<sup>st</sup> engineering run
    - Full-scale chip: TaichuPix3, received in July 2022



TaichuPix1



TaichuPix2



15.9 mm

25.7 mm

TaichuPix3 Pixel size: 25 μm × 25 μm





#### TaichuPix chip architecture



- Pixel 25 μm × 25 μm, Pixel matrix: 512x1024
  - Fast-readout digital, with masking & testing config. logic
- Column-drain readout for pixel matrix
  - Priority based data-driven readout
  - > Time stamp added at the end of column
- 2-level FIFO architecture
  - > L1 FIFO: de-randomize the injecting charge
  - L2 FIFO: match the in/out data rate between core and interface
- Trigger-less & Trigger mode compatible
- Features standalone operation
  - > On-chip bias generation, LDO, slow control, etc.





### Characterization for the TaichuPix chip



Laser test setup



**Radiation test setup** 



#### Spatial resolution on X direction



https://doi.org/10.1016/j.nim a.2023.168601





#### Detection efficiency and cluster size



#### **Detection efficiency**

- With increasing threshold, the efficiency decrease
- Maximum eff. for DUTA is 99.68%, maximum eff. for DUTB is 99.76%

#### Cluster

- The peak value for DUTA is 1 pixel, around 2 pixels for DUTB
- Less charge sharing effects in modified process with full depletion





#### Overview of a baseline vertex detector R&D

- Can break down into sub-tasks
  - ➤ CMOS Pixel Sensor chip R&D
  - Detector Module prototyping

Detector assembly









- Detector module (ladder) = 10 sensors + readout board + support structure + control board
- > Sensors are glued and wire bonded to the flexible PCB, supported by carbon fiber support
- Signal, clock, control, power, ground will be handled by control board through flexible PCB **Challenge**:
- Long flex cable  $\rightarrow$  hard to assemble & some issue with power distribution and delay
- Limited space for power and ground placement

### **Solution**: Readout from both ends, readout compose of three parts, careful design on power placement



#### Laser test for detector module



"CEPCV" pattern by scanning laser on different chips on ladder

# A full ladder includes two identical fundamental readout units

Each contains 5 TaichuPix chips, an interposer board, a FPGA readout board

# Functionality of a full ladder fundamental readout unit was verified

- Configuring 5 chips in the same unit
- > Scanning a laser spot on the different chips with a step of 50  $\mu$ m, clear and correct letter imaging observed

#### Demonstrating 5 chips working together, one ladder readout unit working





#### Double sided one ladder



Vacuum plate for flex and CFRP support fixation











- > An ultralight ladder support is designed to place flex PCB on both sides.
- > Tooling for specific process were designed.
- Wire-bonding for 10 chips on a flex board can be done in IHEP lab

#### Designed by Jinyu Fu,

Ref: https://doi.org/10.1007/s41605-021-00310-4



2023/10/11

# Preparation for the VXD prototype



After installation, flex boards were tested one by one



The outer barrel is under installation



The transparent cover serves as a ventilation duct



The full VXD setup was measured at lab



For DESY beam test, a special flight ticket was bought for VXD (Vertex Detector) prototype.



2023/10/11



#### Introduction of DESY TB21



Ref: <u>Test Beams at DESY</u> https://doi.org/10.1016/j.nima.2018.11.133

- Electron-positron synchrotron DESY II
- Beams are converted bremsstrahlung

beams from carbon fibre targets

- ➢ Up to 1000 particles per cm<sup>2</sup>
- ➤ Energies from 1 to 6 GeV,
- ➢ Energy spread of ~5% and a

divergence of ~1mrad.





#### SETUP at DESY TB21



# Only two chips were assembly on one flex board



- All equipment fits in the 3D
  stage at DESY TB21 hut.
- A bigger collimator (2.5x2.5cm<sup>2</sup>) was used to focus on the center of two TaichuPix3 chips.
- The outermost layer temperature was reduced to 28°C from 40°C with the fan or dry ice.





# Preliminary spatial resolution







- 21 chips are working on the prototype.
- Beamline spot was recorded correctly.
- On flex is set as DUT, the rest chips are set as a telescope.
- Spatial resolution is around

	L0-L1	L1-L2	L2-L3	L3-L4	L4-L5
L(mm)	21.2	20.6	37.46	20.6	21.2

Preliminary offline results indicate a good performance for the vertex detector prototype.





### Detection efficiency and cluster size



#### Cluster

- Cluster size decreases with rising threshold.
- Overall cluster size of full depletion is smaller.

#### **Detection efficiency**

- With increasing threshold, the efficiency decrease
- Maximum eff. for DUT<sub>mod</sub> is 99.1%, maximum eff. for DUT<sub>std</sub> is 99.2%.
- More offline analysis is undergoing.





#### Summary

- Full size TaichuPix prototype is developed and tested, which shows a good spatial resolution(< 5 μm) and radiation hardness.</li>
- First CEPC silicon vertex detector prototype was realized
- Two setups are tested in DESY II TB21 beamline, which indicate a spatial resolution better than 5  $\mu m$ , and detection efficiency better than 99.5%.



Concept (2016)



#### Vertex detector prototype(2023)





#### Test beam contribution at DESY TB21

#### • On Site team (DESY)

- Joao (IHEP) Project leader
- Zhijun Liang (IHEP) test beam coordinator
- Tianya Wu (IHEP) Shift leader , ASIC expert
- Ming Qi (NJU) Shift leader
- Lei Zhang (NJU) Shift leader
- Xiaomin Wei (NWPU) ASIC experts
- Jia Zhou (IHEP) DAQ
- Xinhui Huang (IHEP) Assembly
- Shuqi Li (IHEP) Offline
- Wei Wang (IHEP) Offline
- Hao Zeng (IHEP) Offline
- XueWei Jia (IHEP) Offline

#### Remote support

- WeiWei, Ying Zhang (IHEP) ASIC
- Jun Hu, Ziyue Yan (IHEP) firmware
- Hongyu Zhang (IHEP) DAQ
- Jinyu Fu, Mingyi Dong (IHEP) Assembly
- Gang Li, Linhui Wu (IHEP) Offline
- Yiming Hu, Xiaoxu Zhang (NJU)...





# Thanks for your attention!





#### Introduction

- Building a standalone offline analysis framework for CEPC vertex detector TaiChu pixel chip test beam
- Track reconstruction

   no magnetic
   straight line fit
   no considering multi-scattering currently
- Track alignment

correction for the misalign chip position misalignment effects the resolution of detector find the solution of real geometry for global tracks based on global  $\chi^2$ 

- TaiChu silicon pixel detector
- Pixel size: 25 um
- Theoretical resolution: 25um/sqrt(12) ~ 7.22 um
- The experimental resolution should be better than theoretical Residual: distance of measured hit with the intersection point of track in the measured chip







### Track reconstruction

- 6 layer chips
- 4cm between each other
- electron beam energy 3-6 GeV
- One of the chips is the detector under test (dut), the others are the telescope
- Steps for track finding and reconstruction
- Finding hits in every chip with same time stamp of FPGA (+/- 1)
- Forming adjacent hits into a cluster
- No considering multiple clusters on one chip for one track currently
- Track fitting
- least squares line fitting

$$x = a1z + b1;$$

y = a2z + b2; Chi2 definition:  $\chi^2(\alpha) = \sum_{i=1}^n \frac{f(x_i, \alpha) - e_i)^2}{\sigma_i^2}$ , sigmax = sigmay = 25um/sqrt(12)







Method - millepede matrix method

•

p: alignment parameters, q: track parameters

minimize:  $X^2 = \sum_{i \in tracks} \vec{r}_i^T V_i^{-1} \vec{r}_i$  r is residual  $\vec{r}_i (\vec{p}, \vec{q}_i)$ , V is the covariance matrix

$$\frac{d\chi^{2}(\vec{p})}{d\vec{p}} = 0 \longrightarrow \chi^{2}(\vec{p}) = \chi^{2}(\vec{p}_{0}) + \frac{d\chi^{2}(\vec{p})}{d\vec{p}} \Big|_{\vec{p} = \vec{p}_{0}} \left(\vec{p} - \vec{p}_{0}\right) \longrightarrow \underbrace{\left(\underbrace{J^{T}V_{i}^{-1}J}_{c}\right)\Delta\vec{p}}_{C \ \Delta\vec{p} = \vec{b}} \xrightarrow{J^{T}V_{i}^{-1}\vec{r}_{i}(\vec{p}_{0})}_{C \ \Delta\vec{p} = \vec{b}}$$

- invert the Matrix C to find alignment correction  $\Delta p$
- reduce matrix C for alignment only

 $C_{11}$ 

 $C_{21}$ 

$$S = C_{11} - C_{12} C_{22}^{-1} C_{21}$$

$$\frac{|C_{12}|}{|C_{22}|} \left( \frac{\Delta \vec{p}_1}{\Delta \vec{p}_2} \right) = \left( \frac{\vec{b}_1}{\vec{b}_2} \right) \longrightarrow \left( \frac{\Delta \vec{p}_1}{\Delta \vec{p}_2} \right) = \left( \frac{S^{-1}}{|C_{22}|} - S^{-1}C_{21}^T C_{22}^{-1} - S^{-1}C_{21}^T C_{22}^{-1}}{|C_{22}|} \right) \left( \frac{\vec{b}_1}{\vec{b}_2} \right) \longrightarrow \Delta \vec{p}_1 = S^{-1} \left( \vec{b}_1 - C_{21}^T C_{22}^{-1} \vec{b}_2 \right)$$

- Matrix S with smaller size than C, and  $C_{\rm 22}$  is easy to invert
- Six alignment parameters considered
  - Translation along X, Y, Z direction
  - Rotation around X, Y, Z axis





# Offline reconstruction and alignment

#### **Track Reconstruction**

- No magnetic field
- Least squares fitting (Straight line fit)
- No considering multi-scattering now

#### Alignment

- Using Millepede (c++ version) matrix method
- Correct for the misalignment chip position
- Evaluate the influence of different alignment parameters on spatial resolution







Designed by Shuqi Li





#### Preliminary spatial resolution with laser





- Laser was scanning with a step of 1 μm on the back of the TaichuPix2.
- Trace of two pixels' response can be figured out clearly on the hit map.
- Preliminary analysis of the data shows a spatial resolution less than 4.5 µm.





### **Detection efficiency**

Efficiency definition:

$$\epsilon = \frac{N_{|x_{meas}, y_{meas} - x_{pre}, y_{pre}| < d}}{N_{tel}^{Tracks}}$$

Made by Shuqi Li

- with increasing threshold, the efficiency decrease
- $\cdot$  minimum eff. for DUT\_A is 97%, minimum eff. for DUT\_B is 89%

